

# In-house X-ray Standing Wave study of LaN/B multilayer mirrors

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### The reconstruction of the multilayer period

Samples: 2 periodic La/B and LaN/B multilayer mirrors:

- One baseline sample with clear intermixing between the 2 layers;
- Passivation of La with nitrogen reduces intermixing between the La and B layers;
  - $\rightarrow$  XSW was used to study the width of La distribution.



### **Fluorescence Measurements**

- systems.

## Model independent approach to XSW data analysis



To find P(z): the system of linear equations to be solved:

Experimental scheme: classical scheme for GIXR measurements +

θ

Sample

specular reflection

 $\rightarrow$  The La barrier in the passivated sample has less intermixing with the B barrier than for the baseline sample  $\rightarrow$  Expected result is a good confirmation of the effectiveness of the XSW technique.

### Application example: analysis of multilayer contamination

XSW analysis of small Iron traces

- $\rightarrow$  Iron can enter the system during deposition
- $\rightarrow$  This can lead to a very small periodical contamination which is invisible to any non-

Iron atoms in this multilayer were found in the interfaces.

![](_page_0_Figure_40.jpeg)

 $0 \ 0 \ 0 \ -1$ 

-1 0 0 0

-1 0 0 0 -1 2

 $\lambda$  – regularization coefficient

-1

D =

-0.52 -0.50 deg ).48 0.46 5 10 15 20 25 30 35 40 Fluorescence yeld, a.u. Reflection, a.u. Period depth, Å

Effective EM field from the periodic part of the La/B MLM in the first Bragg reflection condition (center graph), calculated GIXR (left graph) and fluorescence yield from La and B (right graph), and the  $\delta$  profile used for calculation of EM field (top graph).

### Conclusion

- $\rightarrow$  Model independent GIXR analysis allows a fast optical constant profile
  - determination for following XSW analysis;

![](_page_0_Figure_46.jpeg)

**Acknowledgements.** We acknowledge the support of the Industrial Focus Group XUV Optics at the MESA+ Institute at the University of Twente, notably the industrial partners ASML, Carl Zeiss SMT AG, PANalytical, SolMates, TNO, and Demcon, as well as the Province of Overijssel and the Foundation FOM.

 $\rightarrow$  The XSW technique is atomic sensitive which allows it also to differentiate between layers and materials that do not show any optical contrast;

 $\rightarrow$  It is capable of discerning small differences in intermixing between 2 layers.

 $\rightarrow$  Allows to find very small contaminations in thin films and also locate them.

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![](_page_0_Figure_56.jpeg)